

**Notice of References Cited**

Application/Control No.

10/760,464

Applicant(s)/Patent Under  
Reexamination  
RICH ET AL.

Examiner

Rodney G. McDonald

Art Unit

1795

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**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-4,762,728	08-1988	Keyser et al.	438/437
*	B	US-4,426,246	01-1984	Kravitz et al.	438/714
	C	US-			
	D	US-			
	E	US-			
	F	US-			
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	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

**FOREIGN PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
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**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Terashige et al. "Influence of Microstructural Variation on Electrical Properties of SiC Microthermistors", IEEE Transactions on Electron Devices, pp. 555-560, Vol. 46, No. 3, March 1999.
	V	
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	X	

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.